

Title (en)

MICROELECTROMECHANICAL INERTIAL SENSOR WITH ATMOSPHERIC DAMPING

Title (de)

MIKROELEKTROMECHANISCHER INERTIALSENSOR MIT ATMOSPHAERISCHER BEDAEMPUNG

Title (fr)

CAPTEUR INERTIEL MICROÉLECTROMÉCANIQUE AVEC AMORTISSEMENT ATMOSPHÉRIQUE

Publication

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Application

EP 09723766 A 20090325

Priority

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Abstract (en)

[origin: WO2009118355A1] The present invention relates to an inertial sensor, preferably an acceleration sensor or multi-axis acceleration sensor as a microelectromechanical construction element, said sensor comprising a housing with at least one first gas-filled cavity in which a first detection unit is disposed moveably relative to the housing for detection of an acceleration to be detected, wherein the inertial sensor comprises a damping structure.

IPC 8 full level

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CPC (source: EP US)

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Citation (search report)

See references of WO 2009118355A1

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DOCDB simple family (publication)

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